Attorney Docket No.: 55752US019

Amendments to the Claims

Please amend claims 1, 7, 10, 11, 19-21, 26, 32, 34, 35, 40, 41, 43-45, 50, 51, 55-57 and 59-61 as shown below in marked form:

- 1. (currently amended): A process for dry converting a moving web substrate of indefinite length passing from an unwind reel to a takeup reel comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure.
- 2. (original): A process according to claim 1 comprising conveying the substrate through a series of interconnected close enclosures.
- 3. (original): A process according to claim 1 comprising conveying the substrate in a close enclosure or series of close enclosures through at least a first dry converting station in the process.
- 4. (original): A process according to claim 1 comprising conveying the substrate in a close enclosure or series of close enclosures through at least a last dry converting station in the process.
- 5. (original): A process according to claim 1 comprising conveying the substrate in a close enclosure or series of close enclosures from at least a first dry converting station in the process through at least a last dry converting station in the process.
- 6. (original): A process according to claim 1 comprising conveying the substrate in a close enclosure or series of close enclosures from at least a first dry converting station in the process up to a takeup reel or up to or through a packaging station.

- 7. (currently amended): A process according to claim 1 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, the process further comprising conveying the substrate in a close enclosure or series of close enclosures from a cabinet containing an unwind reel to a cabinet containing a takeup reel.
- 8. (original): A process according to claim 1 wherein at least two close enclosures have different pressures, temperatures, average headspaces or average footspaces.
- 9. (original): A process according to claim 1 comprising maintaining or establishing a positive pressure in at least one close enclosure and maintaining or establishing a negative pressure in at least one other close enclosure.
- 10. (currently amended): A process according to claim 1 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, the process further comprising supplying a conditioned gas stream to at least the first in a series of interconnected close enclosures whereby the conditioned gas is carried along with the moving substrate to a downstream close enclosure or pushed to an upstream enclosure or process.
- 11. (currently amended): A process according to claim 1 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, the process further comprising supplying conditioned gas streams to a plurality of close enclosures and withdrawing gas from a plurality of close enclosures.
- 12. (original): A process according to claim 1 comprising supplying conditioned gas streams to each in a series of interconnected close enclosures.

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13. (original): A process according to claim 1 comprising sealing the moving substrate at the upstream and downstream ends of a series of interconnected close enclosures.

- 14. (original): A process according to claim 1 comprising maintaining a pressure gradient of at least about -0.5 Pa or higher in a close enclosure.
- 15. (original): A process according to claim I comprising maintaining a positive pressure gradient in a close enclosure.
- 16. (original): A process according to claim 1 comprising connecting first and second enclosures having a material difference in their respective operating pressures via a close enclosure comprising a transition zone.
- 17. (original): A process according to claim 16 wherein there is a ten-fold or greater pressure difference between atmospheres in the first and second enclosures.
- 18. (original): A process according to claim 1 wherein the total of the average headspace and average footspace in a close enclosure is 10 cm or less.
- 19. (currently amended): A process according to claim 1 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein the total of the average headspace and average footspace in a close enclosure is 5 cm or less.
- 20. (currently amended): A process according to elaim 1 claim 19 wherein the total of the average headspace and average footspace in any close enclosure is 3 cm or less.

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21. (currently amended): A process according to claim 1 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein a first chamber having a gas introduction device is positioned near a control surface, a second chamber having a gas withdrawal device is positioned near the control surface, the control surface and first and second chambers together define a region wherein adjacent gas phases possess an amount of mass, at least a portion of the mass from the adjacent gas phases is transported through the gas withdrawal device by inducing a flow through the region, and the mass flow can be segmented into the following components:

- M1 means total net time-average mass flow per unit of substrate width into or out of the region resulting from pressure gradients,
- M1' means the total net time-average mass flow of a gas per unit width into the region through the first chamber from the gas introduction device,
- M2 means the time-average mass flow of conditioned gas per unit width from or into the at least one major surface of the substrate into or from the region,
- M3 means total net time-average mass flow per unit width into the region resulting from motion of the material, and
- M4 means time-average rate of mass transport through the gas withdrawal device per unit width.
- 22. (original): A process according to claim 21 wherein M1 has a value less than zero and greater than -0.25 kg/second/meter.
- 23. (original): A process according to claim 21 wherein M1 has a value less than zero and greater than -0.10 kg/second/meter.
- 24. (original): A process according to claim 1 comprising flowing a stream of conditioned gas at a rate sufficient to reduce a close enclosure particle count by 75% or more.

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25. (original): A process according to claim I comprising flowing streams of conditioned gas at a rate sufficient to reduce the close enclosure particle counts by 90% or more.

- 26. (currently amended): An apparatus for converting a moving web substrate of indefinite length passing from an unwind reel to a takeup reel, the apparatus comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure.
- 27. (original): An apparatus according to claim 26 wherein the substrate is conveyed through a series of interconnected close enclosures.
- 28. (original): An apparatus according to claim 26 wherein the substrate is enveloped by a close enclosure or series of close enclosures through at least a first dry converting station in the apparatus.
- 29. (original): An apparatus according to claim 26 wherein the substrate is enveloped by a close enclosure or series of close enclosures through at least a last dry converting station in the apparatus.
- 30. (original): An apparatus according to claim 26 wherein the substrate is enveloped by a close enclosure or series of close enclosures from at least a first dry converting station in the apparatus through at least a last dry converting station in the apparatus.
- 31. (original): An apparatus according to claim 26 wherein the substrate is enveloped in a close enclosure or series of close enclosures from at least a first dry converting station in the apparatus up to a takeup reel or up to or through a packaging station.

- 32. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein the substrate is enveloped in a close enclosure or series of close enclosures from a cabinet containing an unwind reel to a cabinet containing a takeup reel.
- 33. (original): An apparatus according to claim 26 wherein at least two close enclosures have different average headspaces or average footspaces.
- 34. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein a conditioned gas stream is supplied to at least the first in a series of interconnected close enclosures and the conditioned gas is carried along with the moving substrate to a downstream close enclosure or pushed to an upstream enclosure or process.
- 35. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein conditioned gas streams are supplied to a plurality of close enclosures and gas streams are withdrawn from a plurality of close enclosures.
- 36. (original): An apparatus according to claim 26 wherein conditioned gas streams are supplied to each in a series of interconnected close enclosures.

- 37. (original): An apparatus according to claim 26 having seals with respect to the moving substrate at the upstream and downstream ends of a series of interconnected close enclosures.
- 38. (original): An apparatus according to claim 26 wherein a close enclosure has a pressure gradient of at least about -0.5 Pa or higher.
- 39. (original): An apparatus according to claim 26 wherein a close enclosure has a positive pressure gradient.
- 40. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, the apparatus further comprising first and second enclosures having a material difference in their respective operating pressures connected by a close enclosure comprising a transition zone between the first and second enclosures.
- 41. (currently amended): An apparatus according to elaim 42 claim 40 wherein there is a tenfold or greater pressure difference between atmospheres in the first and second enclosures.
- 42. (original): An apparatus according to claim 26 wherein the total of the average headspace and average footspace in a close enclosure is 10 cm or less.
- 43. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein the total of the average headspace and average footspace in a close enclosure is 5 cm or less.

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- 44. (currently amended): An apparatus according to elaim 26 claim 43 wherein the total of the average headspace and average footspace in any close enclosure is 3 cm or less.
- 45. (currently amended): An apparatus according to claim 26 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein a first chamber having a gas introduction device is positioned near a control surface, a second chamber having a gas withdrawal device is positioned near the control surface, the control surface and first and second chambers together define a region wherein adjacent gas phases possess an amount of mass, at least a portion of the mass from the adjacent gas phases can be transported through the gas withdrawal device by inducing a flow through the region, and the mass flow can be segmented into the following components:
 - M1 means total net time-average mass flow per unit of substrate width into or out of the region resulting from pressure gradients,
 - M1' means the total net time-average mass flow of a gas per unit width into the region through the first chamber from the gas introduction device,
 - M2 means the time-average mass flow of conditioned gas per unit width from or into the at least one major surface of the substrate into or from the region,
 - M3 means total net time-average mass flow per unit width into the region resulting from motion of the material, and
 - M4 means time-average rate of mass transport through the gas withdrawal device per unit width.
- 46. (original): An apparatus according to claim 45 wherein M1 has a value less than zero and greater than -0.25 kg/second/meter.
- 47. (original): An apparatus according to claim 45 wherein M1 has a value less than zero and greater than -0.10 kg/second/meter.

- 48. (original): An apparatus according to claim 26 wherein a stream of conditioned gas flows at a rate sufficient to reduce a close enclosure particle count by 75% or more.
- 49. (original): An apparatus according to claim 26 wherein the streams of conditioned gas flow at a rate sufficient to reduce the close enclosure particle counts by 90% or more.
- 50. (currently amended): A process for dry converting a moving web substrate of indefinite length passing from an unwind reel to a takeup reel comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to cause a material change in a physical property of interest for the atmosphere in the close enclosure.
- 51. (currently amended): An apparatus for converting a moving web substrate of indefinite length passing from an unwind reel to a takeup reel, the apparatus comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to cause a material change in a physical property of interest for the atmosphere in the close enclosure.
- 52. (previously presented): An apparatus according to claim 51 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 10 cm or less.
- 53. (previously presented): A process according to claim 50 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 10 cm or less.
- 54. (previously presented): An apparatus according to claim 49 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 10 cm or less.

- 55. (currently amended): An apparatus according to claim 49 for converting a moving substrate of indefinite length comprising a dry converting station and substrate-handling equipment for conveying the substrate through the dry converting station, the substrate being enveloped in the dry converting station by a close enclosure supplied with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, wherein the streams of conditioned gas flow at a rate sufficient to reduce the close enclosure particle counts by 90% or more and the total of the average headspace and average footspace in a close-coupled enclosure is 3 cm or less.
- 56. (currently amended): An apparatus according to elaim 49 claim 55 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 2 cm or less.
- 57. (currently amended): An apparatus according to elaim 49 claim 55 wherein the total of the average beadspace and average footspace in a close-coupled enclosure is 1.5 cm or less.
- 58. (previously presented): A process according to claim 25 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 10 cm or less.
- 59. (currently amended): A process according to claim 25 for dry converting a moving substrate of indefinite length comprising conveying the substrate through a dry converting station in a close enclosure while supplying the enclosure with one or more streams of conditioned gas flowing at a rate sufficient to reduce materially the particle count in the close enclosure, the process comprising flowing streams of conditioned gas at a rate sufficient to reduce the close enclosure particle counts by 90% or more, wherein the total of the average headspace and average footspace in a close-coupled enclosure is 3 cm or less.
- 60. (currently amended): A process according to elaim 25 claim 59 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 2 cm or less.
- 61. (currently amended): A process according to elaim 25 claim 59 wherein the total of the average headspace and average footspace in a close-coupled enclosure is 1.5 cm or less.